



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Pablo I. Rovira; ;
Assignee: Nanometrics Incorporated
Title: Optical Metrology System with Combined Interferometer and Ellipsometer
Serial No.: 10/016,943 Filing Date: December 13, 2001
Examiner: Samual A. Turner Group Art Unit: 2877
Docket No.: NAN051 US Confirmation No.: 7400

Santa Clara, California
May 5, 2004

Mail Stop Issue Fee
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §1.97(i)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, §1.97(i) and §1.98, the Applicants submit in the above-identified patent examination the document listed on the accompanying Form PTO-1449. A copy of the documents is also submitted herewith. Applicants request that this document is placed in the file.

This Information Disclosure Statement is submitted pursuant to 37 CFR §1.97(i).
Accordingly, a fee is not required.

The information contained in this Information Disclosure Statement under 37 C.F.R. §1.555 is to the best of my knowledge and is not to be construed as a representation that: (i) a complete search has been made; (ii) additional information material to the examination of this application does not exist; (iii) the information, protocols, results and the like reported by third parties are accurate or enabling; or (iv) the above information constitutes prior art to the subject invention.

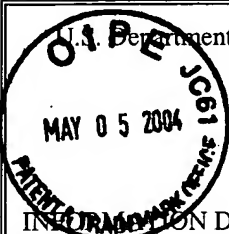
**Via Express Mail Label No.
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Respectfully submitted,

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 <p>U.S. Department of Commerce, Patent and Trademark Office</p> <p>INTERSECTION DISCLOSURE STATEMENT BY APPLICANT</p> <p>(Use several sheets if necessary)</p>	Application No.:	10/016,943
	Filing Date:	December 13, 2001
	First Named Inventor:	Pablo I. Rovira
	Group Art Unit:	2877
	Examiner Name:	Samual A. Turner
	Confirmation No.:	7400
	Attorney Docket No.:	NAN051 US

U.S. Patent Documents

*Examiner Initials		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate

Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No

Other Art (Including Author, Title, Date, Pertinent Pages, Etc.)

	3.	F. Abeles, "Methods for Determining Optical Parameters of Thin Films" in Progress in Optics, Vol. II, E. Wolf, Ed. (North Holland Publishing, Amsterdam, 1963), pp. 248-288

Examiner:

Date Considered:

* Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication with applicant.